

RECEIPT

PATENT
8565D-7213

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Teruaki Fukami

Serial No: 09/218,997

Filed: December 22, 1998

For: SILICON WAFER STORAGE
WATER AND SILICON WAFER
STORAGE METHOD



Art Unit: 1712

Examiner: Not assigned

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:
Assistant Commissioner for Patents
Washington D.C. 20231, on
March 15, 1999
Date of Deposit
William H. Wright
Name
Signature Date 03/15/1999

REQUEST FOR CORRECTED FILING RECEIPT

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

Request is hereby made for correction of the filing receipt (copy enclosed) for the above-identified application. Please note that under the Applicant(s), the first name of the applicant "Teruki" is incorrect. It should read - - Teruaki - -.

- ☐ It is believed this is applicant's error, and accordingly, a fee of \$25 is enclosed. If any adjustment to the fee is required, please charge it to Deposit Account No. 12-1820 of the undersigned attorney's firm.
- ☒ It is believed this is a Patent Office error, and accordingly, no fee is enclosed. However if a fee should be required, please charge it to Deposit Account No. 12-1820 of the undersigned attorney's firm.

A copy of this Request is enclosed.

Respectfully submitted,

Date: March 15, 1999

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LOEB & LOEB LLP

By: 

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FILING RECEIPT



UNITED STATES DEPARTMENT OF COMMERCE
Patent and Trademark Office **8565 PD. 7213**
ASSISTANT SECRETARY AND COMMISSIONER
OF PATENTS AND TRADEMARKS **TOSHIMIYA**
Washington, D.C. 20231 **WW18C**

APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTORNEY DOCKET NO.	DRWGS	TOT CL	IND CL
09/218,997	12/22/98	1712	\$838.00	8565D-7213	1	20	4

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Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Application Processing Division's Customer Correction Branch within 10 days of receipt. Please provide a copy of the Filing Receipt with the changes noted thereon.

Applicant(s)

TERUKI FUKAMI, FUKUSHIMA-KEN, JAPAN.

FOREIGN APPLICATIONS-

JAPAN
JAPAN
JAPAN

9-367049
9-369584
10-228675

12/25/97
12/26/97
07/29/98

TITLE

SILICON WAFER STORAGE WATER AND SILICON WAFER STORAGE METHOD

PRELIMINARY CLASS: 525

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DATA ENTRY BY: FORD, EVELYN

TEAM: 04 DATE: 01/25/99